

ABSTRACT

Provided are an FePt-based sputtering target which alone can form an FePt-based alloy-containing thin film usable as a magnetic recording medium without using a plurality of targets, and a process for producing the same.

The FePt-based sputtering target contains Fe, Pt, and a metal oxide, and further contains one or more kinds of metal elements other than Fe and Pt, wherein the FePt-based sputtering target has a structure in which an FePt-based alloy phase and a metal oxide phase containing unavoidable impurities are mutually dispersed, the FePt-based alloy phase containing Pt in an amount of 40 at% or more and less than 60 at% and the one or more kinds of metal elements other than Fe and Pt in an amount of more than 0 at% and 20 at% or less with the balance being Fe and unavoidable impurities and with the total amount of Pt and the one or more kinds of metal elements being 60 at% or less, and wherein the metal oxide is contained in an amount of 20 vol% or more and 40 vol% or less based on the total amount of the target.